

PDMS Stamp fabrication &
Stamp removal



Imprint in AMONIL
with UV light



PDMS Stamp withdrawal



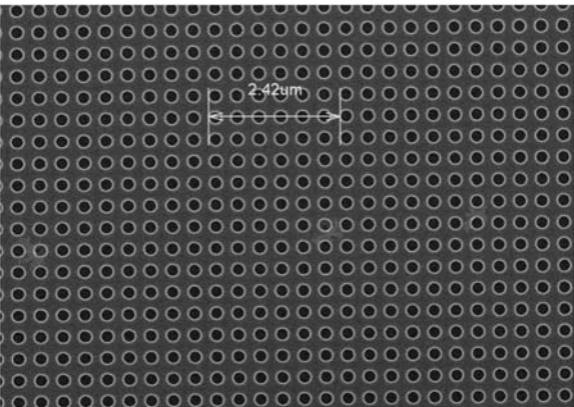
Residual thickness etching
by RIE



Cr/Au evaporation
& lift-off



(a)



(b)